



Infrared Nanophotonics: Materials, Devices, and Applications

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Message from the Guest Editor

Infrared light radiates from almost all the matter on earth and its strategic use will be an important issue for the enhancement of human life and the sustainable development of modern industry. Since it has the frequency in the same region as the phonons or molecular vibrations of the materials, measuring its emission or absorption spectra helps us in characterizing and identifying the materials in a non-destructive manner. Meanwhile, if we can spectroscopically design the infrared emission by tuning the chemical composition or artificially controlling the nano- to mesoscale structures, it will have great impact on industrial applications, such as in thermophotovoltaics, energy-saving drying furnaces, spectroscopic infrared light sources, and various types of infrared sensors.





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Message from the Editor-in-Chief

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